

Notice of References Cited

Application/Control No.

09/530,099

Applicant(s)/Patent Under
Reexamination
YOKOYAMA ET AL.

Examiner

Leland R. Jorgensen

Art Unit

2675

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,754,262	05-1998	Lengyel	349/104
	B	US-5,567,042	10-1996	Farchmin et al.	362/241
	C	US-5,146,354	09-1992	Plesinger	349/59
	D	US-5,779,937	04-1998	Sano et al.	252/310.16
	E	US-5,886,464	03-1999	Shi et al.	313/503
	F	US-5,589,320	12-1996	Ohnishi et al.	430/321
	G	US-5,929,562	07-1999	Pichler	313/506
	H	US-6,160,346	12-2000	Vleggaar et al.	313/512
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	T. Rivera et al., "Reduced Threshold All-Optical Bistability in Etched Quantum Well Microresonators," Appl. Phys. Letter 64(7) February 14, 1994, pp. 869 – 871.
	V	A. Scherer et al., "Fabrication of Microlasers and Microresonator Optical Switches," Appl. Phys. Letter 55 (26), Dec. 25, 1980, pp. 2724 – 2726.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.